	Application No.	Applicant(s)
Notice of Allowability	09/527,873	SHOOSHTARIAN ET AL.
	Examiner	Art Unit
	Hsien-ming Lee	2823
The MAILING DATE of this communication apperature All claims being allowable, PROSECUTION ON THE MERITS IS herewith (or previously mailed), a Notice of Allowance (PTOL-85) NOTICE OF ALLOWABILITY IS NOT A GRANT OF PATENT RI of the Office or upon petition by the applicant. See 37 CFR 1.313 1. This communication is responsive to 6/13/05 &8/9/05.	(OR REMAINS) CLOSED in or other appropriate commercements. This application is	n this application. If not included unication will be mailed in due course. THIS
2. The allowed claim(s) is/are 1,2,4-13,42 and 44-63.		
3. The drawings filed on are accepted by the Examiner 3. The drawings filed on are accepted by the Examiner 3 are accepted by the Examiner 3 are accepted by the Examiner 3 are accepted by the Examiner	r.	
4. Acknowledgment is made of a claim for foreign priority un a) All b) Some* c) None of the: 1. Certified copies of the priority documents have 2. Certified copies of the priority documents have 3. Copies of the certified copies of the priority documents have International Bureau (PCT Rule 17.2(a)). * Certified copies not received: Applicant has THREE MONTHS FROM THE "MAILING DATE"	been received. been received in Applicati cuments have been receive	on No ed in this national stage application from the
noted below. Failure to timely comply will result in ABANDONM THIS THREE-MONTH PERIOD IS NOT EXTENDABLE.		e a reply complying with the requirements
5. A SUBSTITUTE OATH OR DECLARATION must be submitted. Note the attached EXAMINER'S AMENDMENT or NOTICE OF INFORMAL PATENT APPLICATION (PTO-152) which gives reason(s) why the oath or declaration is deficient.		
 6. □ CORRECTED DRAWINGS (as "replacement sheets") mus (a) □ including changes required by the Notice of Draftspers 1) □ hereto or 2) □ to Paper No./Mail Date 25. (b) □ including changes required by the attached Examiner's Paper No./Mail Date Identifying indicia such as the application number (see 37 CFR 1. each sheet. Replacement sheet(s) should be labeled as such in the 	on's Patent Drawing Revie s Amendment / Comment on .84(c)) should be written on	r in the Office action of the drawings in the front (not the back) of
DEPOSIT OF and/or INFORMATION about the deposit attached Examiner's comment regarding REQUIREMENT I		
Attachment(s) 1. ☐ Notice of References Cited (PTO-892) 2. ☐ Notice of Draftperson's Patent Drawing Review (PTO-948) 3. ☑ Information Disclosure Statements (PTO-1449 or PTO/SB/0 Paper No./Mail Date 012304	6. ☐ Interview S Paper No 8), 7. ⊠ Examiner's	informal Patent Application (PTO-152) Summary (PTO-413), /Mail Date S Amendment/Comment
Examiner's Comment Regarding Requirement for Deposit of Biological Material	8. ⊠ Examiners 9. ☐ Other	HSIEN-MING LEE PRIMARY EXAMINER 6/5005

DETAILED ACTION

Remarks

1. The Final rejection has been withdrawn in view of the amendment as follows.

Examiner's Amendment

2. An examiner's amendment to the record appears below. Should the changes and/or additions be unacceptable to applicant, an amendment may be filed as provided by 37 CFR 1.312. To ensure consideration of such an amendment, it MUST be submitted no later than the payment of the issue fee.

Authorization for this examiner's amendment was given in a telephone interview with Jason W. Johnston (Reg. No. 45,675) on August 10, 2005.

3. The application has been amended as follows:

In claim 1 (at line 10), claim 46 (at line 9), claim 48 (at line 9), claim 49 (at line 11) and claim 50 (line 10), insert – directly and – before "selectively."

Allowable Subject Matter

- 4. Claims 1, 2, 4-13, 42 and 44-63 are allowed.
- 5. The following is an examiner's statement of reasons for allowance:

Mahawilli to US 5,814,365 teaches a related art, as stated in the Final rejection. In contrast, Mahawilli neither teaches nor suggests, during one stage of a heat cycle or a cooling stage, providing a gas to *directly and selectively* control a temperature of one of localized regions of a semiconductor wafer to minimize temperature deviation of the one localized region from predetermined temperature. In fact, Mahawilli teaches using a heater assembly 14 to heat the semiconductor wafer 12 with the assistance of a sensor 70 for measuring emission of photons

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from the heated wafer 12 and thus for measuring the wafer temperature. A gas injection manifold 34 can be selectively adjusted to direct different gas flow towards to the center and the perimeter regions of the wafer 12 for the purpose of achieving film deposition uniformity.

Mahawilli, however, does not teach or suggest that the gas injection manifold can directly and selectively control the temperature of the wafer to minimize the temperature deviation of the one localized region on the wafer.

- 6. Any comments considered necessary by applicant must be submitted no later than the payment of the issue fee and, to avoid processing delays, should preferably accompany the issue fee. Such submissions should be clearly labeled "Comments on Statement of Reasons for Allowance."
- 7. Any inquiry concerning this communication or earlier communications from the examiner should be directed to Hsien-ming Lee whose telephone number is 571-272-1863. The examiner can normally be reached on Tuesday-Thursday ($8:00 \sim 6:00$).

If attempts to reach the examiner by telephone are unsuccessful, the examiner's supervisor, Matthew Smith, can be reached on 571-272-1907. The fax phone number for the organization where this application or proceeding is assigned is 703-872-9306.

Information regarding the status of an application may be obtained from the Patent Application Information Retrieval (PAIR) system. Status information for published applications may be obtained from either Private PAIR or Public PAIR. Status information for unpublished applications is available through Private PAIR only. For more information about the PAIR system, see http://pair-direct.uspto.gov. Should you have questions on access to the Private PAIR system, contact the Electronic Business Center (EBC) at 866-217-9197 (toll-free).

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Hsien-ming Lee Primary Examiner Art Unit 2823

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HSIEN-MING LEE
PRIMARY EXAMINEBEL

8/16/2005

August 16, 2005